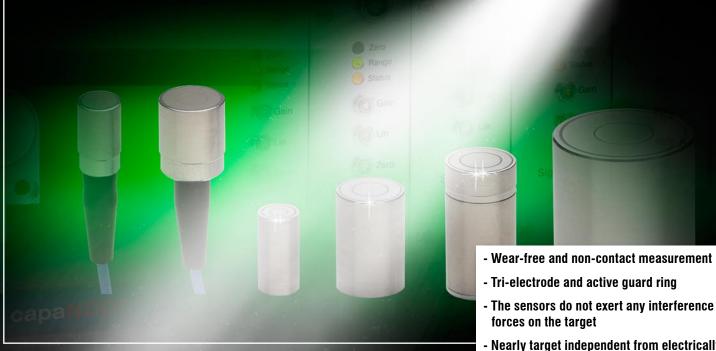


# More Precision.

### capaNCDT

High resolution capacitive displacement sensors and systems.





#### Measuring principle

The principle of capacitive displacement measurement using the capaNCDT (capacitive Non-Contact Displacement Transducer) system is based on how an ideal plate-type capacitor operates. The two plate electrodes are represented by the sensor and opposing measurement object. If a constant alternating current flows through the sensor capacitor, the amplitude of the alternating voltage on the sensor is proportional to the distance between the capacitor electrodes. The alternating current is demodulated and output as, for example, an analogue signal.

forces on the target - Nearly target independent from electrically

conductive measurement objects The capaNCDT system evaluates the reac-

tance of the plate capacitor, which changes in

$$X_C = \frac{1}{j \cdot \omega \cdot C}$$

Capacitance 
$$C = \mathcal{E}_r \cdot \mathcal{E}_0 \cdot \frac{\text{area A}}{\text{distance d}}$$

direct proportion to the distance.

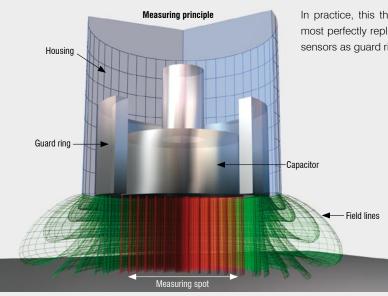
Due to the fact that j  $\omega \; \epsilon_{_{\! 1}} \epsilon_{_{\! 0}}$  and A do not change during measurements, they are sustituted with a constant:

constant K= 
$$\frac{1}{j\omega\epsilon_{\epsilon}\epsilon_{0}A}$$

According to that, the reactance X<sub>c</sub> only depends from the distance:

#### $X_C = constant \cdot distance$

In practice, this theoretical relationship is almost perfectly replicated by the design of the sensors as guard ring capacitors.



#### Use of capacitive sensors

Capacitive sensors are always used if very high accuracy levels are required. The capacitive measuring principle is one of the most precise measurement methods for non-contact displacement measurement.

The measurement principle requires a clean environment where a change of the dielectric  $\epsilon_{\mbox{\tiny r}}$  affects the measurement result. The sensors measure against all electrically conductive materials.

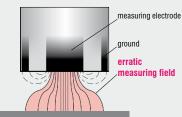
#### Use in a vacuum and clean room

Sensors and sensor cables have proven themselves in clean rooms and under a vacuum. The extremely low gas release is responsible for this. capaNCDT Sensors for ultrahigh vacuum area (UHV) are available on request.

#### Active guard field for high precision measurement

#### **Common capacitive sensors**

Triaxial sensor design



### measuring electrode guard ring electrod homogeneous measuring field guard field

MICRO-EPSILON capaNCDT sensors

The completely triaxial sensor design is unique for capaNCDT sensors, where the guard ring electrode and the grounding are also located on the front edge of the sensor as well as the measurement electrode.

This means capaNCDT sensors can also be installed completely flush in conductive materials. The sensors can also come into contact with each other in the case of multi-channel measurements. Interference of the measuring field is reliably prevented by the triaxial design of the sensor.

#### Active guard triaxial cable

Capacitive measurement systems from Micro-Epsilon operate with a unique, active, low noise cable in combination with an active guard ring capacitor. A particularly high quality signal is achieved due to the double shielding of the field. The system has an almost perfect impermeable electrical shield, which ensures precise measurements. In addition, the guard ring electrode provides a protected, completely homogeneous measuring field for extremely high stability and interference-free, accurate measurements.

#### Rapid sensor replacement without calibration

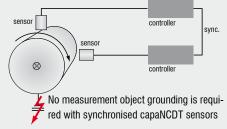
The capacitive measuring principle specially developed by Micro-Epsilon enables the simple change of a sensor in just a few seconds. This simplified replacement of sensors with different measuring ranges and the interchange of different capaNCDT controllers can be easily carried out without any re-calibration. A sensor replacement normally takes around 5 seconds, unlike conventional systems, which have to be subjected to time-consuming calibration and linearisation.



Fast sensor replacement in just 5 seconds! The interchange of various controllers and sensors in the capaNCDT series is performed rapidly without any time-consuming calibration.

#### Non-contact target grounding

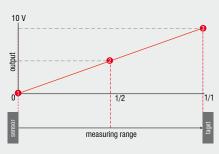
In many applications, grounding of the target is very difficult or even impossible. Unlike conventional systems, the target for synchronisation of two capaNCDT devices does not necessarily have to be grounded. However, maximum signal quality is only achieved when the measurement object is correctly grounded. All measurement objects must be grounded for applications that use DT6019.



The schematic diagram shows two synchronised capaNCDT sensors that are measuring against a roller. As the sensors are connected via Micro-Epsilon's unique synchronisation technology, grounding of the target is unnecessary in most cases.

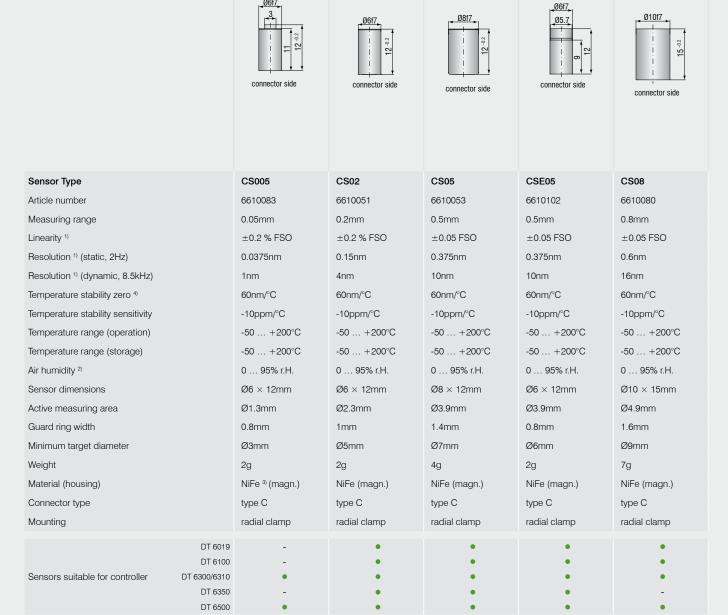
#### Linearisation and calibration

capaNCDT systems are calibrated at the factory for metallic targets (output 0 - 10V). The nominal output characteristic can be optimised by the user for special target materials or difficult installation conditions using the "Zero Point" potentiometer. Three-point linearisation is necessary for insulators as target. The adjustment is made using three distance points (1 = zero point, 2 = measuring range centre, 3 = measuring range end), which are defined as comparison standard.



This calibration can be performed for the capaNCDT 6300 and 6500 models.

#### Cylindrical sensors with female connector



FSO = Full Scale Output

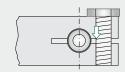
- 1) With controller DT6500
- <sup>2)</sup> Non condensing
- 3) Titanium version available
- 4) Sensor mounted in the mid of clamping area

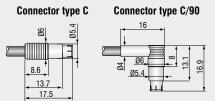
#### Mounting cylindrical sensors

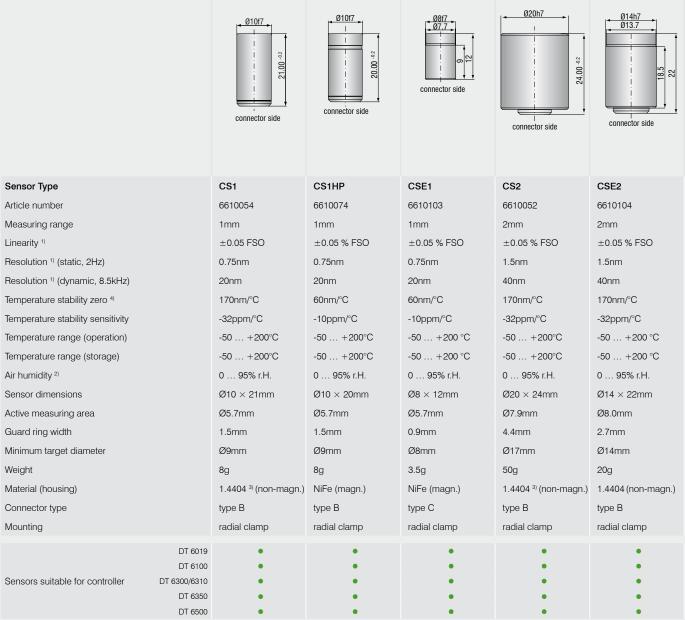
All sensors can be installed as either freestanding or flush mounted. Fastening is carried out using a clamp or collet.

# Mounting with grub screw (plastic)

#### Mounting with collet







FSO = Full Scale Output

- 1) With controller DT6500
- <sup>2)</sup> Non condensing
- 3) Titanium version available
- 4) Sensor mounted in the mid of clamping area

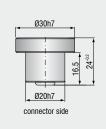
# Connector type B Connector type B/90 25 27 37 010

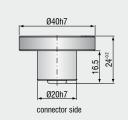
#### Sensors

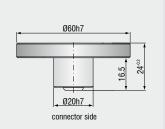
The sensors are designed as guard ring capacitors. They are connected to the signal conditioning electronics with a triaxial cable. The sensor cable is connected to the sensor using a high quality connector. All standard sensors can be used within a maximum deviation of 0.3% without recalibration. Individually matched special sensors are produced on request.

#### Measuring range expansion / reduction

The capaNCDT controller (except the series DT6019) can optionally be configured so that the standard measuring ranges of the sensors are reduced by half or expanded by the factor of 2. The reduction increases the accuracy while the measuring range expansion reduces the accuracy.







Sensor Type	CS3	CS5	CS10	
••				
Article number	6610055	6610056	6610057	
Measuring range	3mm	5mm	10mm	
Linearity 1)	±0.05 % FSO	±0.05 % FSO	±0.05 % FSO	
Resolution 1) (static, 2Hz)	2.25nm	3.75nm	7.5nm	
Resolution 1) (dynamic, 8.5kHz)	60nm	100nm	200nm	
Temperature stability zero 4)	170nm/°C	170nm/°C	170nm/°C	
Temperature stability sensitivity	-32ppm/°C	-32ppm/°C	-32ppm/°C	
Temperature range (operation)	-50 +200°C	-50 +200°C	-50 +200°C	
Temperature range (storage)	-50 +200°C	-50 +200°C	-50 +200°C	
Air humidity 2)	0 95% r.H.	0 95% r.H.	0 95% r.H.	
Sensor dimensions	Ø30 × 24mm	Ø40 × 24mm	Ø60 × 24mm	
Active measuring area	Ø9.8mm	Ø12.6mm	Ø17.8mm	
Guard ring width	8mm	11.6mm	19mm	
Minimum target diameter	Ø27mm	Ø37mm	Ø57mm	
Weight	70g	95g	180g	
Material (housing)	1.4404 (non-magn.)	1.4404 <sup>3)</sup> (non-magn.)	1.4404 <sup>3)</sup> (non-magn.)	
Connector type	type B	type B	type B	
Mounting	radial clamp	radial clamp	radial clamp	
DT 6019	•	•	•	
DT 6100	•	•	•	

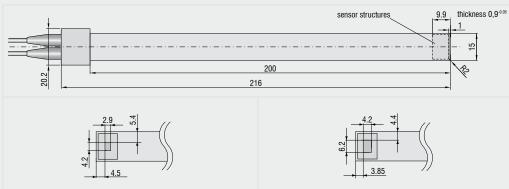
FSO = Full Scale Output

- 1) With controller DT6500
- Non condensingTitanium version available

Sensors suitable for controller

DT 6300/6310 DT 6350 DT 6500

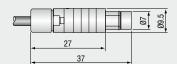
<sup>4)</sup> Sensor mounted in the mid of clamping area

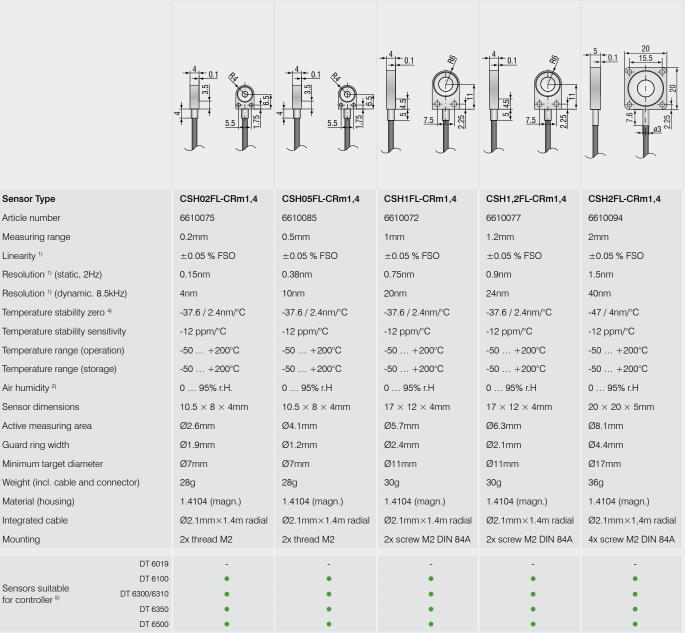


	" "	' ·
Sensor Type	CSG0,50-CAm2,0	CSG1,00-CAm2,0
Article number	6610112	6610111
Measuring range	0.5mm	1mm
Gap width 1)	0.9 - 1.9mm	0.9 - 2.9mm
Linearity 1)	±0.1% FSO	±0.1% FSO
Resolution 1) (static, 2Hz)	4nm	8nm
Resolution 1) (dynamic, 8.5kHz)	90nm	180nm
Temperature stability zero	50nm/°C	50nm/°C
Temperature stability sensitivity	-40ppm/°C	-40ppm/°C
Temperature range (operation)	-50+100°C	-50+100°C
Temperature range (storage)	-50+100°C	-50+100°C
Air humidity <sup>2)</sup>	095%	095%
Sensor dimensions	200 x 15 x 0.9mm	200 x 15 x 0.9mm
Active measuring area	3 x 4.3mm	4.2 x 5.1mm
Guard ring width	2.7mm	2.2mm
Minimum target diameter	approx. 7 x 8mm	approx. 8 x 9mm
Weight	77g	77g
Material (housing)	1.4301	1.4301
Material (sensor)	FR4	FR4
Integrated cable	2m	2m
DT 6019 DT 6100 Sensors suitable for controller DT 6300/6310 DT 6350	•	- • •

Sensor width + measuring range on both sides
 With controller DT6500
 Non condensing

#### Connector type B





FSO = Full Scale Output

- 1) With controller DT6500
- <sup>2)</sup> Non condensing
- 3) Without cable, bend protection and crimp
- 4) In the case of a sensor mounting on the top and underside
- $^{\rm 5)}$  CSH Sensors are matched to controller with standard cable length 1m

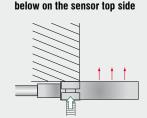
#### Mounting flat sensors

Screw connection from above

on the underside

The flat sensors are attached using a threaded bore for M2 (for the sensors CSH02FL and CSH05FL) or using a through-hole for M2 bolts. The sensors can be bolted from above or below.

# 1 1 1



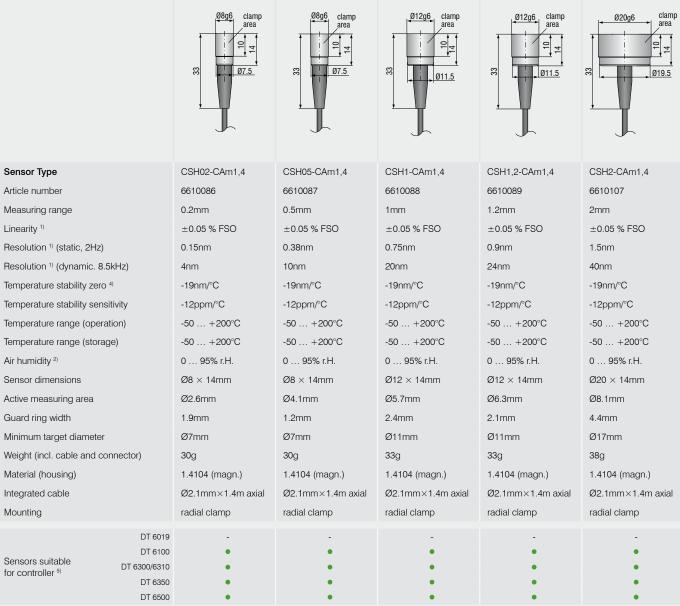
Screw connection from

# cable length 1.4 m sensor

Connector for integrated cables

9

#### Cylindrical sensors with integrated cable



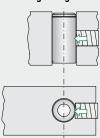
FSO = Full Scale Output

- 1) With controller DT6500
- 2) Non condensing
- 3) Without cable, bend protection and crimp
- Sensor mounted 2mm behind front surface
- 5) CSH Sensors are matched to controller with standard cable length 1m

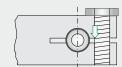
#### Mounting cylindrical sensors

All sensors can be installed as both freestanding and flush units. Fastening is carried out by using a clamp or collet.

#### Mounting with grub screw (plastic)



#### Mounting with collet



#### Important!

All Micro-Epsilon sensors are short circuit proof. Unlike other systems the pre-amplifier will not get damaged, if the front face of the sensor gets shorted by touching the conductive target

#### Accessories

	DT 6019	DT 6100	DT 6300/6310	DT 6350	DT 6500
MC2.5 Micrometer for sensor calibration, range 0 - 2.5mm, Resolution 0.1μm. Suitable for sensors CS005 to CS2		•	•	•	•
MC25D Digital micrometer for sensor calibration, range 0 - 25mm, adjustable offset (zero). Suitable for all sensors.	•	•	•	•	•
SWH.0S.650.CTMSV Vacuum feed through		•	•	•	•
UHV Vacuum feed through		•	•	•	•
PC3/8 Power- and output cable, 3m, 8-pin		•	•	•	
ESC30 Synchronisation cable, 0.3m, necessary for multi channel applications				•	
SC30 Synchronisation cable, 0.3m		•			
PSCC30 Power-/synchronisation cable, necessary for multi channel applications			•		
PS2010 Power supply for DIN rail mounting Input 230 VAC (115 VAC) Output 24 VDC / 2.5 A; L/W/H 120x120x40 mm		•		•	
<b>PS300/15</b> Power supply; output ±15 V / 1 A Input 90 - 264 VAC			•		
CSP 301 Digital signal processing unit with display for synchronous processing of 2 channels		•	•	•	
SCAC3/4 Signal output cable, necessary for multi channel applications			•		

#### **Technical Information**

# Influence of tilting the capacitive sensor

In the case of tilting of the capacitive sensor, a measurement error must be assumed as the geometric conditions of the field for the target change. In fact, the average distance of the sensor remains constant; however, the edge areas move closer or further away from the target. This results in field distortions, which affect the capacity C according to the following model:

$$C_d(\Theta) = C_d(0) * [1 + (\frac{1}{4}) * (\frac{R^2}{d^2}) * \tan^2 \Theta]$$

$$\Delta_{x} = 100*(\frac{d}{d_{MAX}})*\{\frac{1}{[1+(\frac{R^{2}}{4d^{2}})*\tan^{2}\Theta]}-1\}$$

C capacity

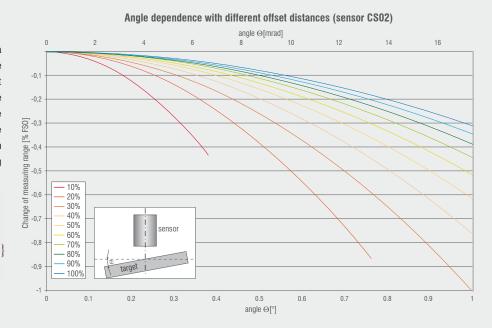
Θ tilt angle

R measurment area radius

d working distance sensor-target

d<sub>MAY</sub> sensor measuring range

 $\Delta x$  signal change



# Example illustration of the influence using the CS02 sensor as an example, consideration of a tilt angle of max. 1° for different sensor distances.

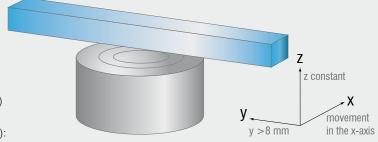
In the case of 10% distance in the sensor axis, there is already contact between sensor housing and target at 0.38°; in the case of 20% distance, the contact is at 0.76°. The simulation can be performed for all sensors and installation conditions; tilt angles around a decentralised tilt point can also be calculated.

#### Measurement on narrow targets

The influence of the target width on the measurement signal is shown using the example of a CS05 sensor.

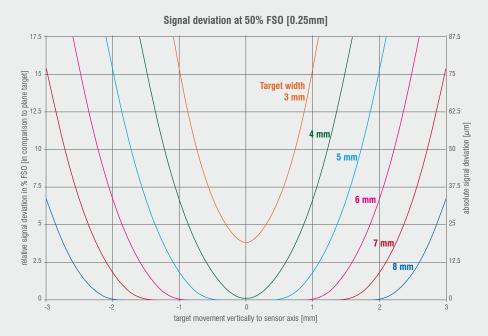
A target extended in the y-axis, narrowed in the x-axis has been varied in different parameters:

- target-sensor distance (z-axis): 0.25mm (measuring range centre)
- width of the target in the x-axis: 3 ... 8mm (21 values)
- displacement of the target in the x-axis (vertical to the sensor axis):
- 0 ... 3mm (13 values)



In each case, the capacity between electrode and target and its reciprocal (this is proportional to the sensor signal of the controller) were calculated. The diagram shows the deviations from the capacity values for a flat target (large opposite sensor in x and y axes) depending on the target width and displacement.

The smaller the distance between sensor and target, the narrower the target can be. In the example, a centrally placed target with a width of 5mm is sufficient to achieve a stable signal in the centre of the measuring range. This proves that the field does not spread beyond the sensor diameter.



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#### Force effects on the target

Alternating forces between the two electrodes are produced by the electrical field:

$$F = \frac{C*U^2}{(2*d)} = constant$$

$$F = \frac{\epsilon_0 * \epsilon_R * A * E^2}{2} = constant$$

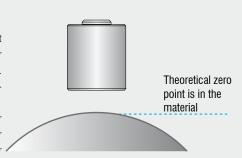
$$F = \frac{1}{2} * E * Q = constant$$

Using the example of a CS1 sensor, which is operated using the DT6300/DT6500 system, a force of approx.  $0.23\mu N$  is produced. The force however is dependent on the selection of sensor and electronics, not on the sensor's position over the measuring range. The DT6019/6100 systems operate using lower measuring currents, whereby the electrical field and the electrical voltage are lower so that the force is only  $0.01\mu N$  and so measurement without feedback is assumed.

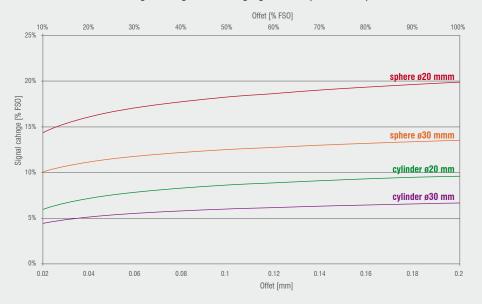
#### Measurements on spheres and shafts

In practice, it is often necessary to measure curved surfaces. A classic example is shaft runout measurements, where a cylindrical target is measured. Compared to a flat target, there are either more or less significant measured value deviations depending on the bending radius in doing so. This is caused by various effects, e.g. concentration of the field lines at the highest point or a capacity increase due to a larger measuring spot.

In reality, it can be assumed that the bending radius results in a virtual zero point, i.e., the sensor value 0 can no longer be achieved. Due to the integrating function of the capacitive senor over the measurement surface, the virtual, average measuring plane lies behind the surface line. For example, this means that with a  $200\mu m$  sensor and a roller with an external diameter of 30mm and a gap clearance of  $20\mu m$ , almost 5% more is indicated, i.e. approx  $30\mu m$ . As this effect can be calculated, corresponding characteristics can be calibrated in the evaluation electronics.



#### Signal change: various target geometries (sensor CS02)



#### **Technical Information**

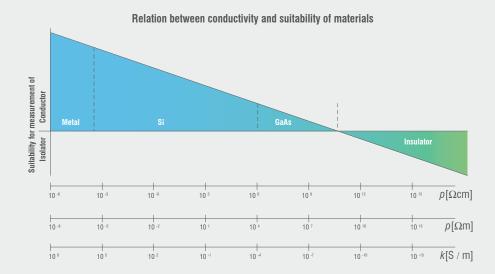
#### Consideration of the conductivity requirements

In order to achieve a linear output signal across the complete measuring range, certain requirements for the target or the counter electrode must be complied with.

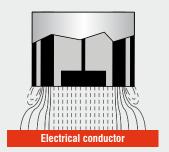
The impedance in the ideal plate capacitor can be shown in the equivalent circuit diagram by a capacitor and a resistor connected in parallel. For measurement against metals, the Ohm part can be disregarded; the impedance is only determined by the capacitive part.

Conversely, only the Ohm part is considered for measurements against insulators. In between, there is the large range of semiconductors. Most semiconductors can be measured very well as electrical conductors. The requirement is that the capacitive part of the total impedance is still significantly larger (>10x) than the ohmic part. This is almost always the case for silicon wafers irrespective of the endowment.

Nevertheless, semiconductors with poor conductivity (e.g. GaAs) can also be measured as conductors under certain circumstances. However, various adjustments are required for this, e.g. reduction of the operating frequency or a temporary, partial increase of the conductivity.



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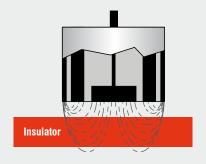
#### Electrical conductor as target

The capaNCDT system measures the reactance Xc of the capacitor, which changes proportionally with distance. The high linearity of the signal is achieved without further electronic circuitry. This particularly applies to measurements against electrically conductive materials (metals). Changes of the conductivity have no influence on linearity or sensitivity. All conductive or semi-conductive targets are measured without any loss in measurement performance.

# No penetration of the fields for electric conductors

As the measurement principle operates without penetration of the fields in the target, even the thinnest targets, e.g.  $10\mu$ m electrically conductive paint, can be measured.

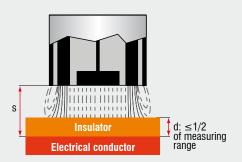
The capacitive measuring process operates with currents in the  $\mu A$  range. This means even the smallest electrical charges are sufficient to make measurements possible. Even very thin metallic objects can guarantee the charge carrier displacement. A target thickness of a few micrometres is sufficient here. The electrical field develops between sensor electrode and target surface; the distance determines the reactance.



#### Insulators as target

Some capaNCDT systems can also measure insulating materials. In this case resolution and accuracy are reduced.

The field lines penetrate the insulator and join with the electrical sensor housing. The reactance Xc depends on the distance between sensor and insulator. Therefore a constant thickness and permittivity of the insulator is necessary. Factory calibration/compensation is strongly recommended.



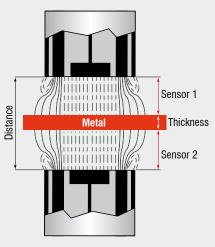
## Thickness measurement of insulators

The capaNCDT system can also be used for the linear thickness measurement of insulators. The field lines penetrate the insulator and join with the electrical conductor. If the thickness of the insulator changes, this influences the reactance Xc of the sensor. The distance to the electrical conductor must therefore be constant.

$$\frac{C}{C_0} = \frac{1}{(1 - (\frac{d}{s}) * (1 - \frac{\epsilon_1}{\epsilon_2}))}$$

$$\epsilon_1 = \epsilon_0 * \epsilon_{rl}, \epsilon_2 = \epsilon_0 * \epsilon_r$$

- d Target thickness
- s Measuring gap
- $\varepsilon_1$  Permittivity air
- $\varepsilon$ , Permittivity insulator

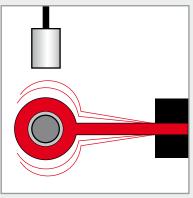


Thickness = Distance - (Sensor 1 + Sensor 2)

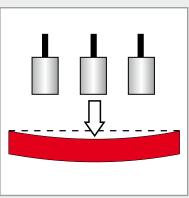
## Thickness measurement of metals

Two-sided thickness measurement of metals is made possible by installing the sensors opposite each other. Strip thicknesses in the  $\mu m$  range can be measured using this method. Each sensor generates a linear output signal dependent on the distance between sensor surface and target surface. If the sensor distance is known, the thickness of the target can be determined easily.

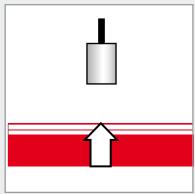
Due to the capacitive principle, the measurement is only performed against the surface without penetrating the target. If the measuring points are synchronised, measurement against non-grounded targets is possible.



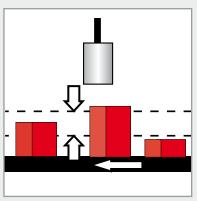
Vibration, amplitude, clearance, run-out



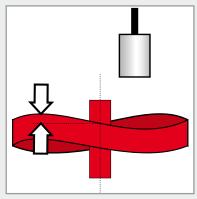
Deflection, deformation, waviness, tilt



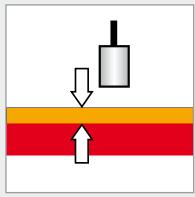
Displacement, distance, position, elongation



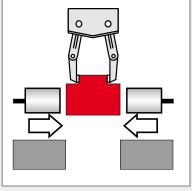
Dimensions, dimensional tolerances, sorting, parts recognition



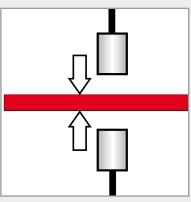
Stroke, deformation, axial shaft oscillation



Thickness measurement of insulating materials



In-process inspection, dimensional inspection



Two-sided thickness measurement

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# Specific sensors for OEM applications

Application examples occur again and again where the standard versions of the sensors and the controller are performing at their limits. For these special tasks, we modify the measuring systems exclusively according to your individual requirements. Changes often requested include for example modified designs, target coordination, mounting options, individual cable lengths, modified measuring ranges or sensors with integrated controller.



Special OEM electronic design



System for measuring the internal diameter of extruder bores



Dual sensor integration for ID check



Customised sensor body



Customised modification for a specific environment

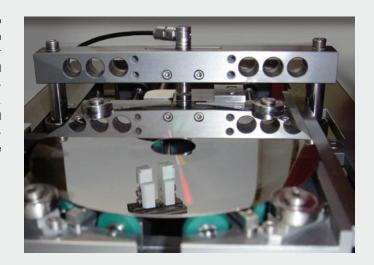


Special OEM design

#### **Application examples**

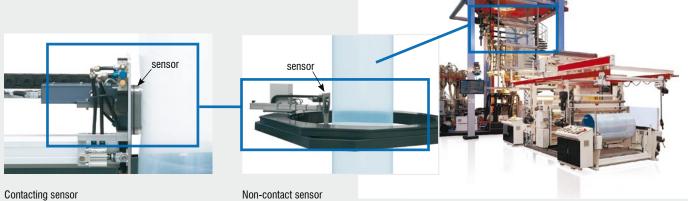
# Thickness measurement of dies for optical data carriers

Previously, the data was transferred to a master system using a laser to reproduce CDs, DVDs, HD-DVDs or Blu-ray discs by pressing. A thin layer of nickel is applied using galvanisation to the silicon or glass carrier (substrate). The absolute thickness values of the nickel layer are required in order for the exact control of the galvanisation bath. Capacitive sensors from Micro-Epsilon are used to measure the thickness and profile. A sensor is positioned above and below the die, which is then moved between the sensors during measurements. Using the two units for distance information, the thickness is determined very precisely using the differential method.



# Modular measuring system for the profile measurement of blown films

The measuring of the film profile already on the film bubble provides important data for extrusion control. In order to make the process as efficient as possible, a modular blown film measuring system was designed by Micro-Epsilon, which is installed immediately after the calibration cage. The system is available with contact and non-contact sensors. The sensor system used for profile measurement is based on the capacitive measuring principle, which reliably and accurately ascertains the profile of the film. The capacitive sensors used can be distinguished by their extreme precision and signal quality.

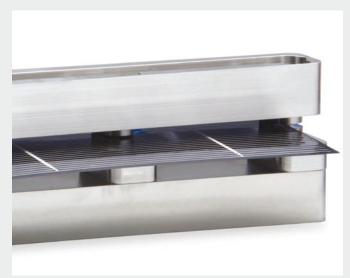


#### Measurements on wafers and semiconductors

Extreme accuracies are required in the semiconductor industry in order to design processes and products efficiently. Capacitive sensors from Micro-Epsilon are used, among other things, for the positioning, displacement measurement and thickness measurement in the semiconductors area.



Capacitive displacement sensors are used for adjustment with nanometre precision of lenses in optical systems for wafer exposure.



Wafer thickness measurement with 3 tracks



Wafer thickness measurement with two capacitive sensors